bonding

W backpate gate oxide Si Channel gate oxide

Si Substrate

handle wafer

handle wafer

LTO

W backgate gafe oxide Si Channel gate oxide

Si Substrate

delamination

Si Substrate

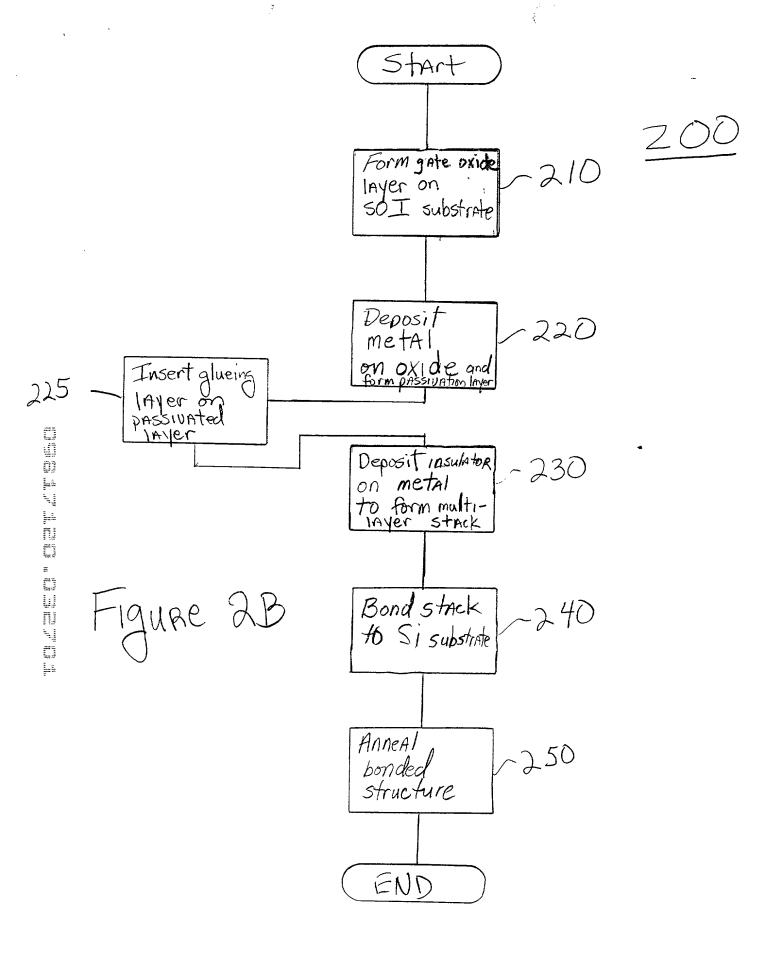
W backgate gale oxide Si Channel gate oxide

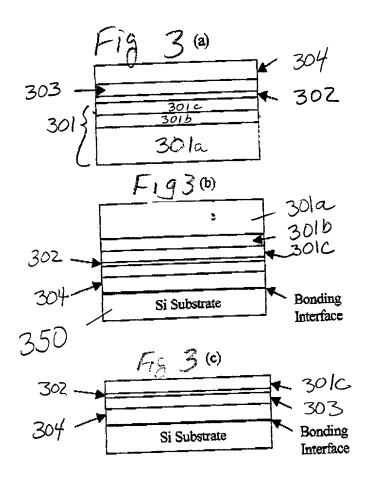
anneal

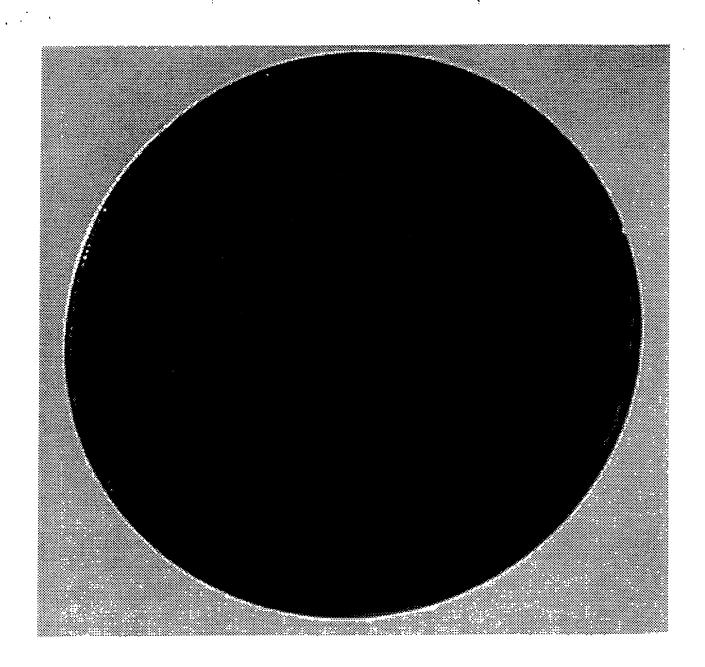
handle wafer

LTO

double-gate device Si Channel gate oxide W backgate handle wafer substrate for handle wafer Si Substrate W backgate
gate oxide
Si Channel
gate oxide 013backside etching annea handle wafer Si Substrate W backgate gate oxide Si Chamel gate oxide OLT handle wafer bonding termediate layer Si Substrate W backgate gate oxide Si Channel gate oxide issivation and







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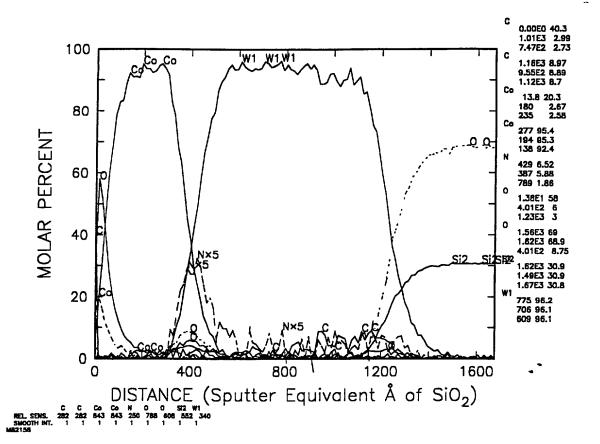


Fig. 5